# Readout System

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## **Outline**

- Current status
- EPI-illuminator R&D
	- Motivation
	- Design guidelines
- Resolution Measurements
	- PSF method
	- ESF method

## Current Readout System



- Same as ESS mechanics
- Custom EPI-illuminator
- 2x Magnification lens
- Motorized polarizer
- 4M camera (563 fps)
- Blue LED (465 nm)
- Pixel size ~ 30 nm
- Scanning speed ~20 mm<sup>2</sup> /h

# EPI-illuminator R&D

# EPI-illuminator R&D



- Nikon EPI:
	- Big and heavy
	- 100W halogen lamp
	- Green filter
	- Diaphragms
	- Diffuser
	- Insufficient light to Image artifacts see particles < 100 nm
- Custom EPI:
	- Compact
	- LED (green, blue, violet)
	- No color filter needed
	- Diffuser
	- No diaphragms
	- Low image contrast
	-



• **Performance of existing illumination systems was not good enough to measure small grains**

# Goals

- Build a custom build a custom illumination system optimized for our needs
	- Brighter illumination
	- Efficient light collection
	- Compact and lightweight
	- LED
	- No filters or diffusors (if possible)
	- Diaphragms (improve contrast and resolution)

## EPI-illumination Principle

- A point-like illumination source placed in the back focus of the objective lens
- A sample is illuminated with a parallel light beam
- Reflected light is collected by the objective within its entire NA



# Optimized Illumination System (ver.1)



- 12 times more powerful than Nikon EPI with 100W halogen lamp and green filter
- Max output light power reaching objective (mW):
	- EPI v.1 18 @ 435 nm (LED)
	- Nikon  $-1.4$  @ 550 nm (halogen)



### Optimized Illumination System (ver.1)



WEIGHT (Total): 0.82 Kgs

25 x 36 mm 50:50 UVFS Plate Beamsplitter, Coating: 400 - 700 nm, t =

• Microscope cost ~800 euro • EPI ver.1 cost ~820 euro

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TOTAL:

820,42 $\epsilon$ 

# Optimized Illumination System (ver.1)

- Custom parts to be produced:
	- Beamsplitter holder
		- Produced at a 3D-printer
	- Cube-to-stage mounting plates









# Resolution Measurements

## Image Formation

• The objective and tube lens do not image a point in the object (for example, a minute hole in a metal foil) as a bright disk with sharply defined edges, but as a slightly blurred spot surrounded by diffraction rings, called Airy pattern



# Resolution definition

- The limit up to which two small objects are still seen as separate entities is used as a measure of the resolving power of a microscope. The distance where this limit is reached is known as the effective resolution of the microscope (**d<sup>0</sup>** )
- **The Rayleigh Criterion:** The principal maximum of the second Airy disk coincides with the first minimum of the first Airy disk
- The definition is independent of SW!



**The Rayleigh Criterion** 



# Approximation of an Airy disk with Gaussian

$$
I(q) \approx I'_0 \exp\left(\frac{-q^2}{2\sigma^2}\right) ,
$$

- $\sigma \approx 0.42 \lambda F$ , if normalized by amplitude
- $\sigma \approx 0.45 \lambda F$ , if normalized by volume
- $Resolution = d_0 = 1.22 \lambda F \approx 2.9 \sigma$
- It is possible to measure the resolution by fitting the central peak of the Airy pattern with the Gaussian
- But one still needs a point source!



# PSF Resolution Measurement Algorithm

- Put a sample with nanoparticles onto stage
- Scan some area
- Reconstruct clusters and grains
- Select the most focused cluster in each grain
- For each selected cluster find minor (= 2*σ*) by elliptical fitting
- Plot all minors and find the mean *μ* of the distribution
- Get the resolution as 1.45 *μ*

#### Resolution Measurement with the PSF method



- Minor =  $170 \pm 4$  nm
- $Resolution = 1.45*$ Minor  $= 246 \pm 6$  nm







Contrast: 245/12

60 nm

 $psf(x,y)$ 

20 nm Contrast: 56/13

750 nm



## PSF, LSF and ESF

#### Point Spread Function (PSF):

- $point(x, y) = \delta(x)\delta(y)$
- $PSF(x, y) = T[point(x, y)] = T[\delta(x)\delta(y)]$

Line Spread Function (LSF):

• 
$$
line(x) = \delta(x) = \int_{-\infty}^{+\infty} \delta(x)\delta(y)dy
$$

• 
$$
LSF(x) = T[line(x)] = \int_{-\infty}^{+\infty} PSF(x, y) dy
$$

Edge Spread Function (ESF):

•  $step(x) = \int_{-\infty}^{x} \delta(x') dx' = \int_{-\infty}^{x} line(x') dx'$ 

• 
$$
ESF(x) = T[step(x)] = \int_{-\infty}^{x} LSF(x')dx'
$$



### Resolution Measurement Method

• LSF(x) =  $\frac{d}{dx}$  $dx$  $ESF(x)$ 

• It is possible to obtain LSF profile by differentiating ESF profile! But also:

• 
$$
LSF(x) = \int_{-\infty}^{+\infty} PSF(x, y) dy = \int_{-\infty}^{+\infty} A \exp\left(-\frac{x^2}{2\sigma_x^2} - \frac{y^2}{2\sigma_y^2}\right) dy =
$$

$$
= A \exp\left(-\frac{x^2}{2\sigma_x^2}\right) \int_{-\infty}^{+\infty} \exp\left(-\frac{y^2}{2\sigma_y^2}\right) dy = \sqrt{2\pi}\sigma_y A \exp\left(-\frac{x^2}{2\sigma_x^2}\right)
$$

- It is possible to measure  $\sigma_x$  by fitting the LSF profile with Gaussian!
- Resolution  $\approx 2.9\sigma$

# ESF Resolution Measurement Algorithm

- Put an object micrometer onto stage with the ticks perpendicular to the X axis
- Take an image of the object's edge
- Get the ESF profile by averaging profiles for every line of pixels
- Get the LSF profile by differentiating numerically the ESF profile
- Get  $\sigma$ <sub>x</sub> by fitting the LSF profile
- Get the resolution as 2.9  $\sigma_{\rm x}$

#### Resolution Measurement with the Edge method



- Use an object micrometer as a sample
- Uses the ESF of a sharp edge to measure the resolution
- Resolution =  $221 \pm 6$  nm
- The resolution is similar to that of the PSF method







 $Edge(x)$   $ESF(x)$ 

### INTRINSIC ANGULAR RESOLUTION

- Neutron test Beam sample (FNS exposure)
- Compare clusters with elliptical ( $e > 1.1$ ) shape with the proton recoil direction
- Scattering contribution negligible



#### POSITION ACCURACY



(pixel size 28 nm)

#### Accuracy of 10 nm on both coordinates

### Planned Improvements

- Revise optical design to improve light collection and make the EPI shorter
- Use a beam-splitter cube instead of the mirror
	- Does not polarize transmitted/reflected light -> better for plasmon analysis
	- Does not shift transmitted light -> easier to align
	- Strong back reflection from sides -> worse contrast
- Use a smaller size LED
	- Produces less heat
	- Can render the aperture diaphragm unnecessary -> more compact design
- Replace the mechanical polarization rotator with a one based on liquid crystals
	- Reduce vibrations

# Thank You!